KSDT

Korean International Semiconductor Conference & Exhibition
on Manufacturing Technology 2025

KISM 2025 BUSAN

Re:Innovation of Semiconductor Manufacturing for AI Ecosystem

[ThA2] Nanoscale Thin Film Deposition VII

Session Date	November 13 (Thu.), 2025
Session Time	10:50-12:00
Session Room	Room A (Capri Room, 2F)
Session Chair	Prof. Changhwan Choi (Hanyang Univ., Korea)

[ThA2-1] [Invited] **10:50-11:20**

Atomic Layer Deposition Process Development of Molybdenum Dioxide for the DRAM Capacitor Electrode Applications

Chaeyeong Hwang, Soo Min Yoo, and Woojin Jeon (Kyung Hee Univ., Korea)

[ThA2-2] [Invited] **11:20-11:40**

Optimization of Atomic Layer Deposition Chemistry Toward Advanced Semiconductor Applications

Woo-Jae Lee (Pukyong Nat'l Univ., Korea)

[ThA2-3] **11:40-12:00**

Improved Thermal Stability and Retention in Carbon-Doped $Ge_2Sb_2Te_5$-Based Phase-Change Random Access Memory

Jisu Park, Wooseong Son, Seung Min Kang, and Changhwan Choi (Hanyang Univ., Korea)